

## WHAT IS CLAIMED IS:

1. An exposure apparatus which transfers a pattern onto a substrate with exposure light, comprising:
  - a partition wall which encloses a path of
- 5 exposure light and isolates the path from surroundings; and
  - a connecting member in a tubular form which connects a structure supported independently of said partition wall and said partition wall and sustains
- 10 airtightness in a space enclosed with said partition wall,
  - wherein a section of said connecting member, taken in a direction perpendicular to an axis of said connecting member, has a three-dimensional portion.
- 15 2. The apparatus according to claim 1, wherein the section of said connecting member has a plurality of three-dimensional portions.
3. The apparatus according to claim 1, wherein said connecting member connects the structure and said partition wall in an axially compressed state.
- 20 4. The apparatus according to claim 1, wherein said connecting member is made of a material selected from the group consisting of resin and rubber.
5. The apparatus according to claim 1, wherein said connecting member is made of fluororubber.
- 25 6. The apparatus according to claim 1, wherein said connecting member is made of a material having a

1. The apparatus according to claim 1, wherein said connecting member is arranged to be resistant to a gage thickness of not more than 2 mm.
- 5 8. The apparatus according to claim 1, wherein the pressure of not more than 1 MPa.
- 10 8. The apparatus according to claim 1, wherein the tubular form includes a structure which has a polygonal section with a three-dimensional portion.
- 15 9. The apparatus according to claim 1, wherein the tubular form includes a structure which has a circular section with a three-dimensional portion.
- 20 10. The apparatus according to claim 1, wherein the structure is supported by a vibration isolating mechanism, and said partition wall is supported by a structure which can transmit vibrations to said partition wall.
- 25 11. The apparatus according to claim 10, wherein said partition wall is supported by a support member which receives vibrations from a floor.
12. The apparatus according to claim 10, wherein said partition wall connects to a second structure other than the structure through a second connecting member, and the second connecting member has the same structure as a structure of said connecting member.
13. The apparatus according to claim 1, wherein the structure is supported by a structure which can transmit vibrations to the structure, and said partition wall is supported through a vibration

isolating mechanism.

14. The apparatus according to claim 1, wherein a stage is arranged in the space enclosed with said partition wall.

5 15. A device manufacturing method comprising:  
a step of transferring a pattern onto a substrate using an exposure apparatus as defined in claim 1; and  
a step of developing the substrate.